



Docket No.: 49657-961

PATENT

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of

Kenji ITOGA, et al.

Serial No.: 09/769,490

Group Art Unit: 2882

Filed: January 26, 2001

Examiner: C. Kao

For: X-RAY EXPOSURE APPARATUS, X-RAY EXPOSURE METHOD, X-RAY MASK, X-RAY MIRROR, SYNCHROTRON RADIATION APPARATUS, SYNCHROTRON RADIATION METHOD AND SEMICONDUCTOR DEVICE

Mail Stop Non-Fee Amendment with Extension of Time

Commissioner for Patents

P.O. Box 1450

Alexandria, VA 22313-1450

Dear Sir:

Transmitted herewith is an Amendment in the above-identified application.



No additional fee is required.

Applicant is entitled to small entity status under 37 CFR 1.27

Also attached: Petition for Extension of Time (1-month)

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The fee has been calculated as shown below:

	NO. OF CLAIMS	HIGHEST PREVIOUSLY PAID FOR	EXTRA CLAIMS	RATE	FEE
Total Claims	39	48	0	\$18.00 =	\$0.00
Independent Claims	4	6	0	\$84.00 =	\$0.00
Multiple claims newly presented					\$0.00
Fee for extension of time					\$110.00
Total of Above Calculations					\$0.00
					\$110.00

- ☒ Please charge my Deposit Account No. 500417 in the amount of \$110.00. An additional copy of this transmittal sheet is submitted herewith.
- ☒ The Commissioner is hereby authorized to charge payment of any fees associated with this communication or credit any overpayment, to Deposit Account No. 500417, including any filing fees under 37 CFR 1.16 for presentation of extra claims and any patent application processing fees under 37 CFR 1.17.

Respectfully submitted,

MCDERMOTT, WILL & EMERY

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Date: July 28, 2003



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X-RAY MIRROR, SYNCHROTRON RADIATION APPARATUS, SYNCHROTRON
RADIATION METHOD AND SEMICONDUCTOR DEVICE

AMENDMENT

Mail Stop Non-Fee Amendment
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

The following Amendment and Remarks are submitted in response to the Office Action
dated March 27, 2003. The claims are presented in the revised amendment format.

#211 D
marsha
8/29/03

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